

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re patent application of

Cabral, Jr. et al.

Serial No.: 09/902,483

Group Art Unit: 2813

Filing Date: July 11, 2001

Examiner: Unknown

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b5  
11-23-01

For: SELF-ALIGNED SILICIDE (SALICIDE) PROCESS FOR LOW RESISTIVITY  
CONTACTS TO THIN FILM SILICON-ON-INSULATOR AND BULK MOSFETS  
AND FOR SHALLOW JUNCTIONS

Assistant Commissioner of Patents  
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following documents listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copies of the listed documents are provided herewith for the convenience of the Examiner.

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit Account No. 50-0510.

Respectfully submitted,

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Date: September 19, 2001  
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